

EDITORIAL

The 19th MicroMechanics Europe Workshop (MME 2008)

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The 19th MicroMechanics Europe Workshop (MME 2008)

Guest Editor

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This special issue of *Journal of Micromechanics and Microengineering* is devoted to the 19th MicroMechanics Europe Workshop (MME 08), which took place at the RWTH Aachen University, Aachen, Germany, from 28–30 September, 2008.

The workshop is a well recognized and established European event in the field of micro system technology using thin-film technologies for creating micro components, micro sensors, micro actuators, and micro systems.

The first MME Workshop was held 1989 in Enschede (The Netherlands) and continued 1990 in Berlin (Germany), 1992 in Leuven (Belgium), and then was held annually in Neuchâtel (Switzerland), Pisa (Italy), Copenhagen (Denmark), Barcelona (Spain), Southampton (UK), Ulvik in Hardanger (Norway), Gif-sur-Yvette (France), Uppsala (Sweden), Cork (Ireland), Sinaia (Romania), Delft (The Netherlands), Leuven (Belgium), Göteborg (Sweden), Southampton (UK), and in Guimarães (Portugal).

The two day workshop was attended by 180 delegates from 26 countries all over Europe and from Armenia, Austria, Bulgaria, Canada, China, Cuba, Iran, Japan, Korea, Malaysia, Taiwan, Turkey, and the United States of America. A total of 97 papers were accepted for presentation and there were a further five keynote presentations.

I am proud to present 22 high-quality papers from MME 2008 selected for their novelty and relevance to *Journal of Micromechanics and Microengineering*. All the papers went through the regular reviewing procedure of IOP Publishing. I am eternally grateful to all the referees for their excellent work. I would also like to extend my thanks to the members of the Programme Committee of MME 2008, Dr Reinoud Wolffenbuttel, Professor José Higinio Correia, and Dr Patrick Pons for pre-selection of the papers as well as to Professor Robert Puers for advice on the final selection of papers. My thanks also go to Dr Ian Forbes of IOP Publishing for managing the entire process and to the editorial staff of *Journal of Micromechanics and Microengineering*.

I trust that this special issue will provide new trends of the emerging field of micro system technology and I hope you enjoy reading it.